

Precise underfill dispense in high-throughput chip-on-wafer packaging

Dr. Hanzhuang Liang

Nordson ASYMTEK
Carlsbad, CA

Underfill for chip level packaging

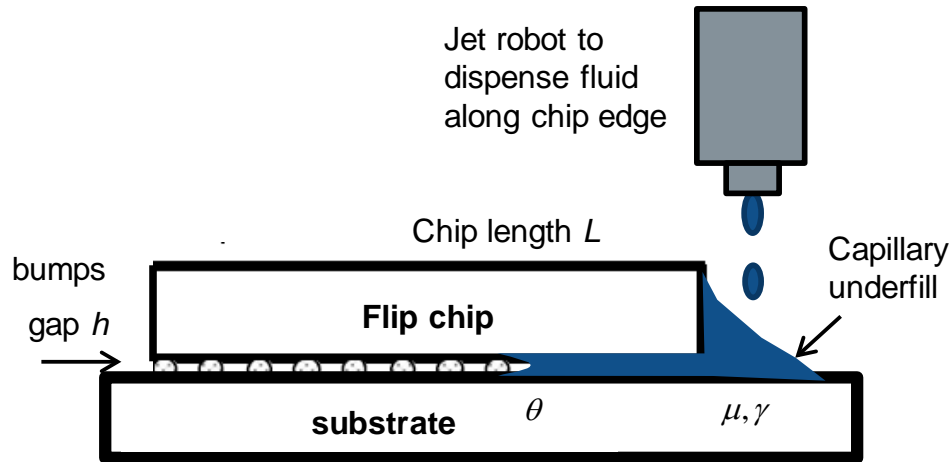
- Outline
 - Underfill process
 - Chip level underfill: chip-on-wafer, chip-on-BGA
 - Challenge and solution
 - Advantage of high end dispenser
- Summary

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Capillary underfill for flip chip packaging

Schematic of flip chip underfill



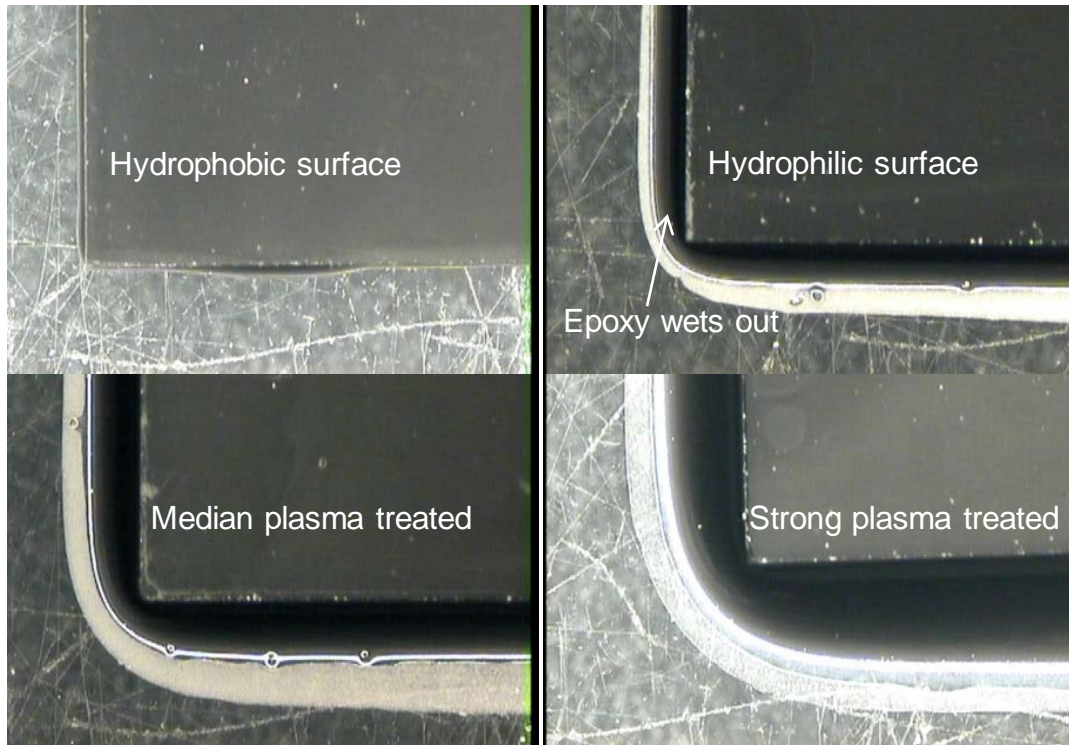
Capillary underfill

Underfill: fluid flows into the gap by capillary force

Capillary flow out time

$$T = 3\mu L^2 / (h\gamma \cos \theta)$$

Underfill: epoxy wet-out zone

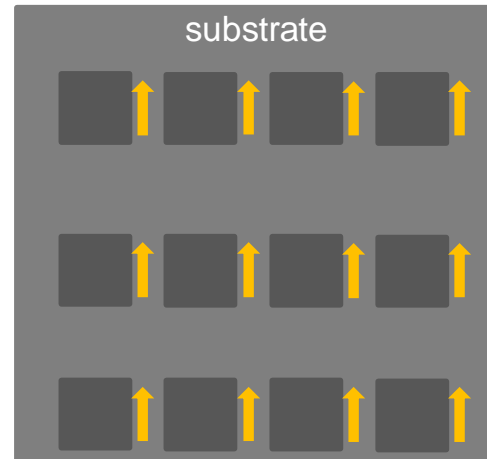
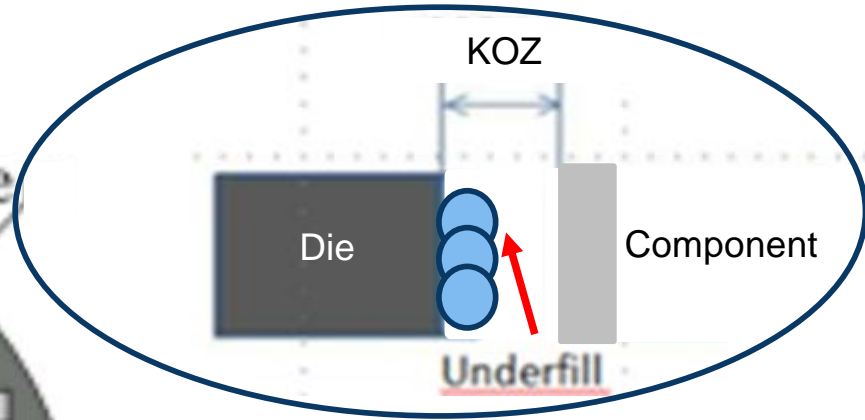
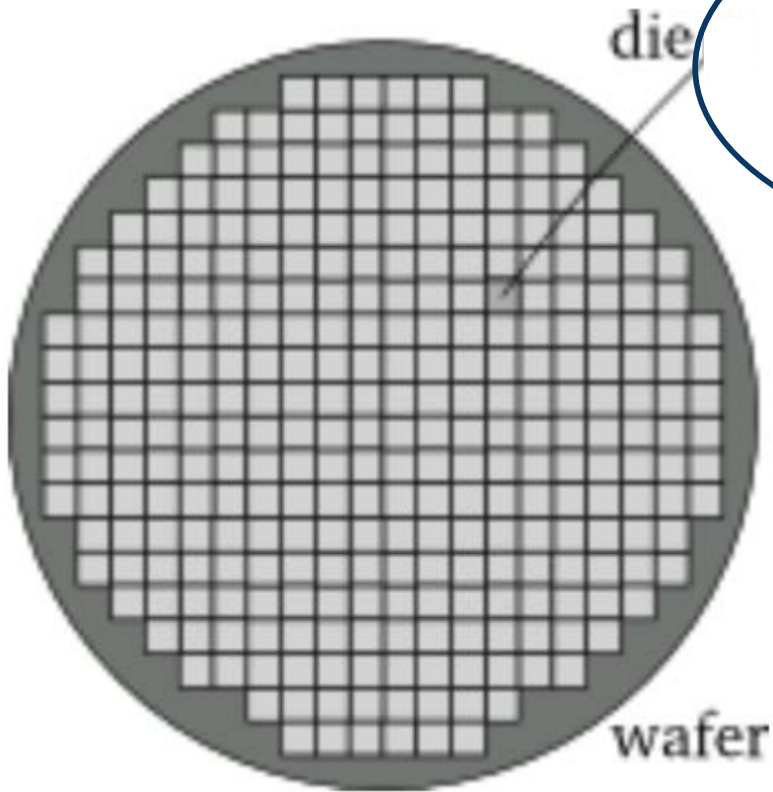


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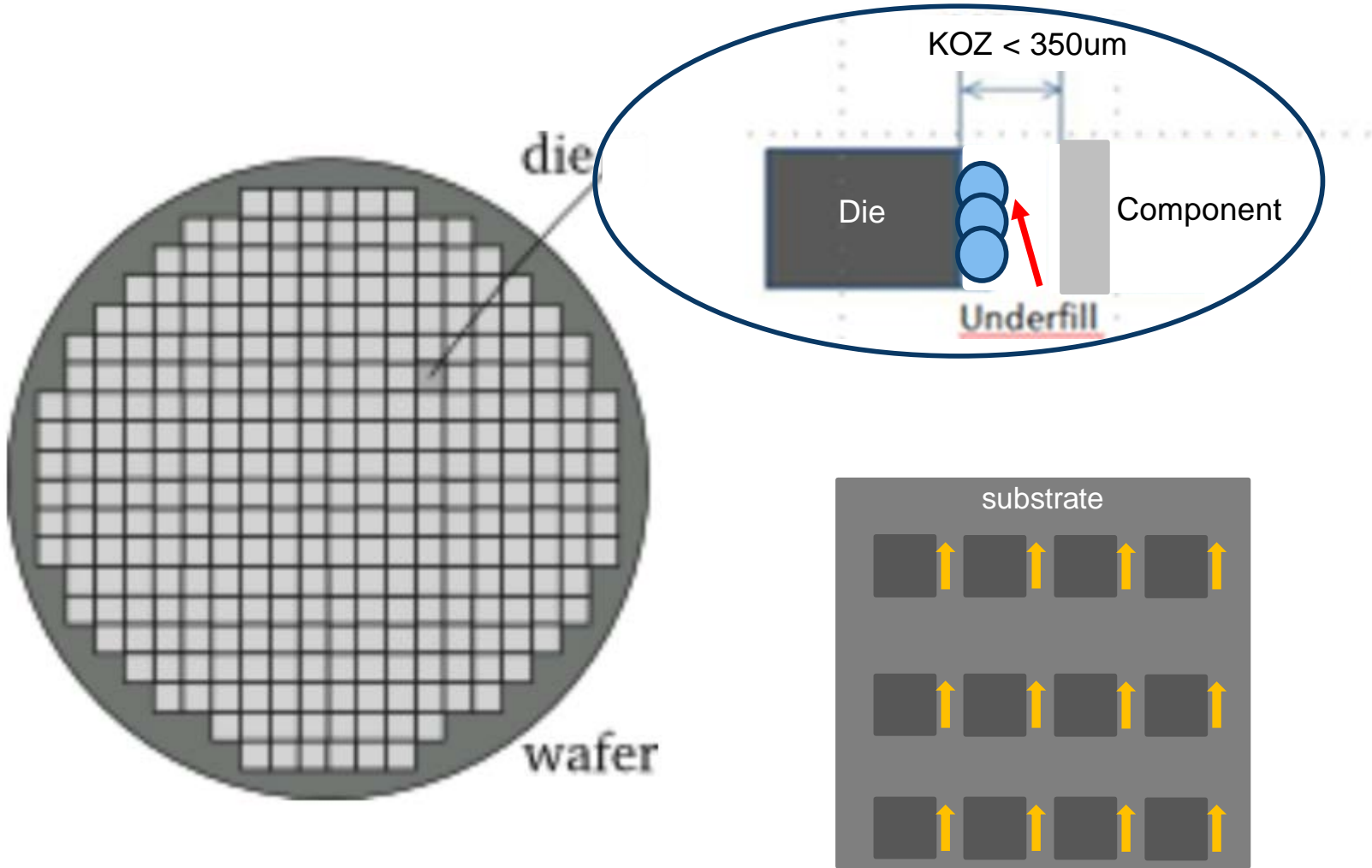
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Chip-on-wafer underfill

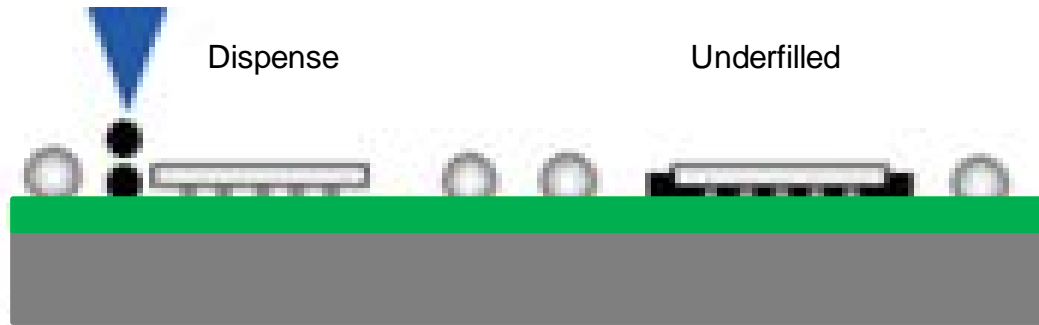
KOZ 5-10mm for board level underfill
<1mm for today's chip-level UF



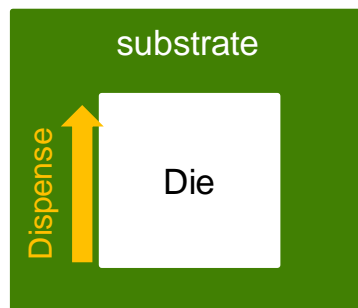
Chip-on-wafer underfill



Flip-chip on BGA underfill



Underfill process: side view

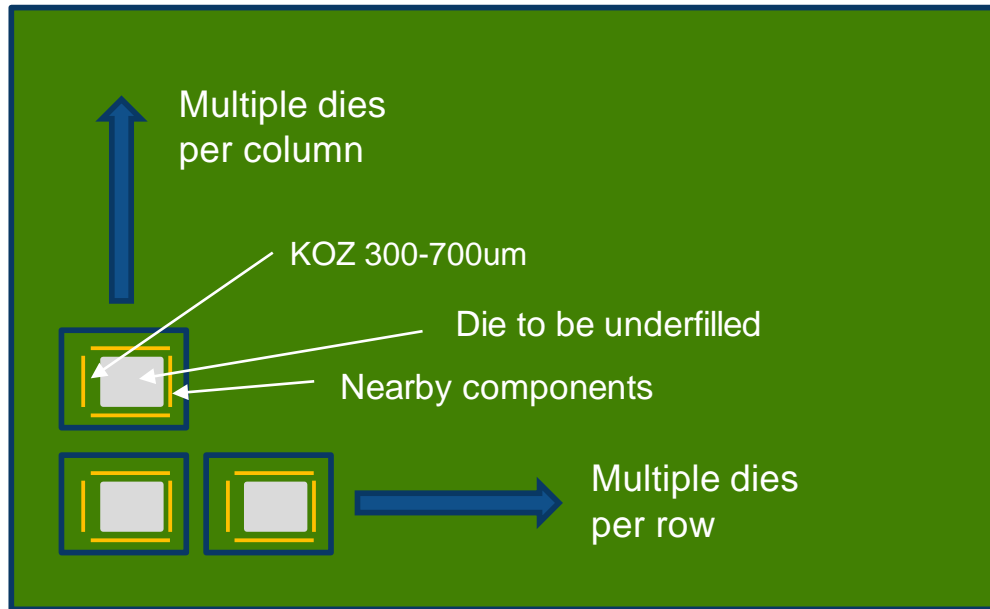


Top view

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Chip level underfill criteria: KOZ 300-700um at UPH 4000-7000



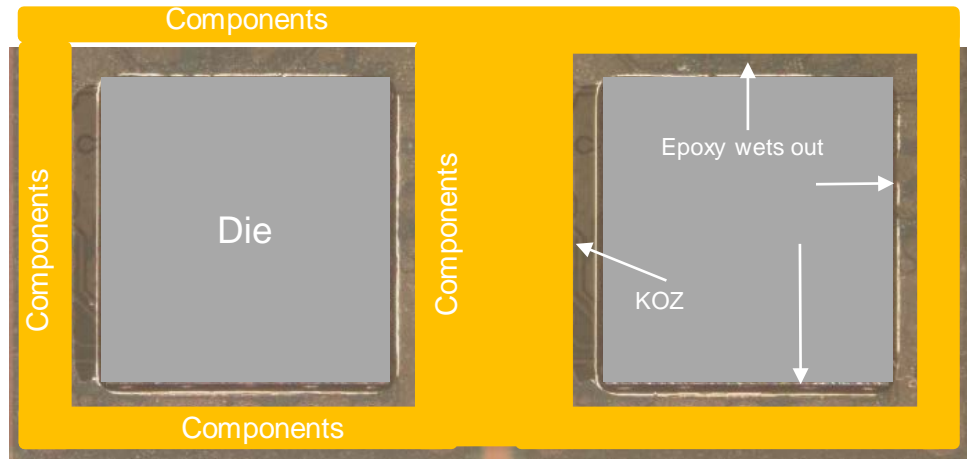
Chip level underfill with die and components densely populated

400-900 units per board

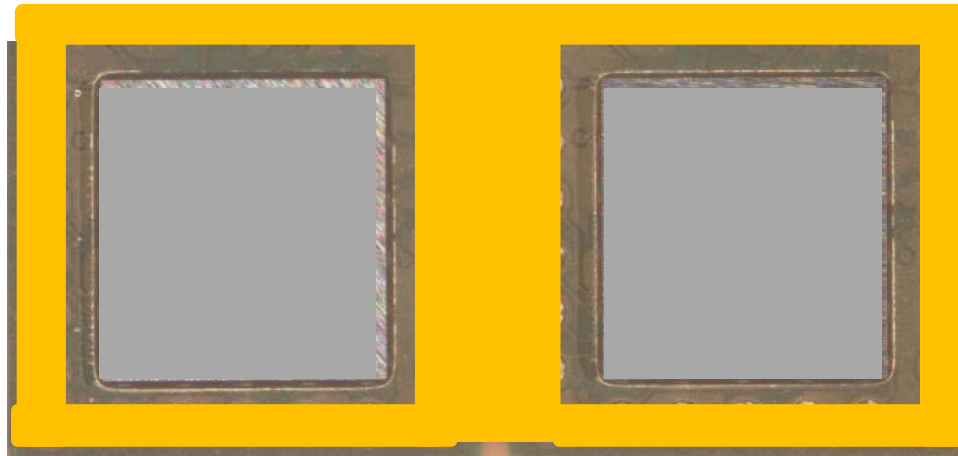
Throughput 4000-7000 unit per hour

KOZ 1-2mm in 2015, 700um in 2016, 300-500 in 2016-2017

Chip level underfill solution: KOZ 300-500um at UPH 4000-7000



(a) KOZ=300-700um after dispense



(b) Epoxy cured by heat

Underfill for chip level packaging

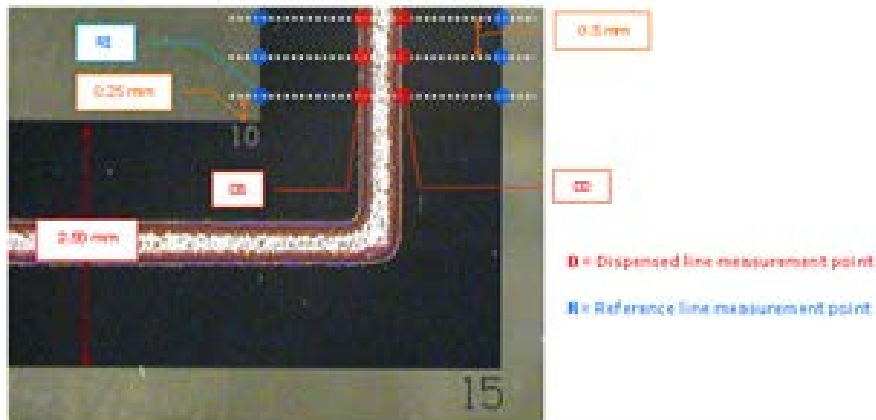
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Advanced dispenser solution

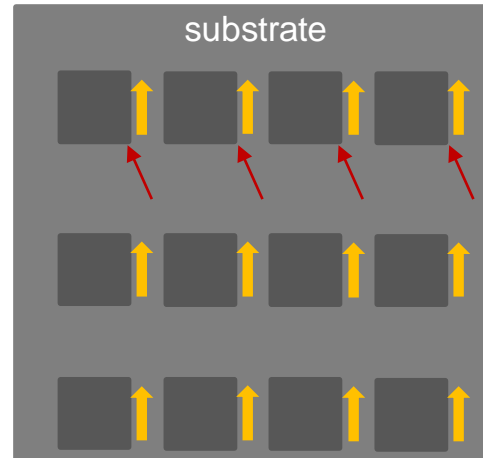
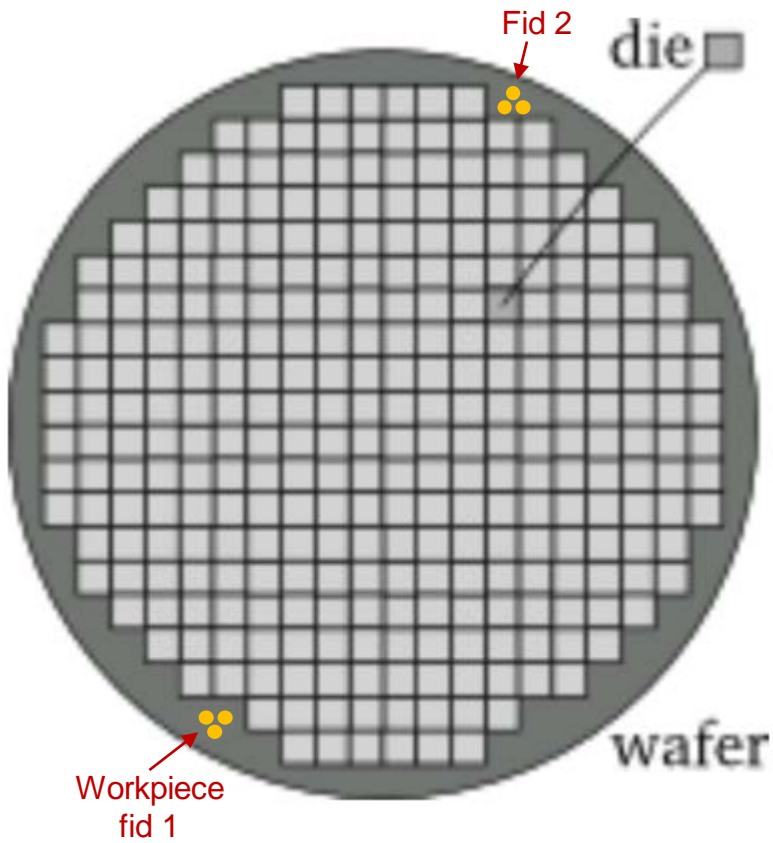


Advanced dispenser solution: high accuracy platform

- A dispenser platform achieved the high accuracy.
 - X and Y axis wet dispense accuracy $\pm 40\mu\text{m}$ @ 3σ
- To verify the accuracy, placement error was measured as the positional offset between the center of the reference line and the center of the dispensed lines.



Advanced dispenser solution: vision to locate each die



Pattern:
die
Corner fid 1

Advanced dispenser solution: thin stream jetting

- 50 μg dot with 1.6 specific gravity: 400- μm diameter sphere in air.
- 16 μg dot: 270- μm diameter sphere.
- A newly developed jetting applicator achieved the small dot size and in-air width with;
 - New jet-cartridge design
 - PZT actuator
 - Actuation velocity
 - Stroke control
 - High firing frequency 500-800Hz
- 8 μg dot: 500um KOZ
- 3 μg dot: 400um KOZ



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Summary

- Backgrounds of underfill process
- Underfill for chip-on-wafer and chip-on-BGA
- Challenge and fail/pass criteria: small KOZ, high UPH
- Solution launched in production line
 - The platform achieved $\pm 40\mu\text{m}$ @ 3σ in X and Y axis accuracy
 - The applicator demonstrated small dot dispensing to achieve sub-500um KOZ
 - Higher jetting frequency 500-800 Hz to maintain high UPH 4000-7000
 - The software contributed to applicator operation, vision detection, features for high UPH

Contact

Hanzhuang “Hannah” Liang, PhD PE
Phone 760-930-3313, Fax 760-918-8332
Hannah.liang@nordsonasymtek.com

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“Underfill dispensing for Chip-on-wafer”, Semicon China CSTIC 2017 Symposium

By Akira Morita, Weiwei Gu & Brian Chung

Focus on dispensing small dots through 350um gap between chips